



EV078335270

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. .... 09/388,826  
Filing Date ..... September 1, 1999  
Inventor ..... Weimin Li et al.  
Assignee ..... Micron Technology, Inc.  
Group Art Unit ..... 2813  
Examiner ..... E.J. Kielin  
Attorney's Docket No. .... MI22-1208  
Title: Low k Interlevel Dielectric Layer Fabrication Methods

**RESPONSE TO JUNE 4, 2002 OFFICE ACTION**

#28/F  
9/12/02  
Jumo

To: Box Fee Amendment  
Assistant Commissioner for Patents  
Washington, D.C. 20231

From: Frederick M. Fliegel, Ph.D.  
Tel. 509-624-4276; Fax 509-838-3424  
Wells St. John P.S.  
601 W. First Avenue, Suite 1300  
Spokane, WA 99201-3828

Sir:

Responsive to the Office Action dated June 4, 2002, Applicant amends  
and remarks as follows: